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PATENT APPLICATION  
ATTORNEY DOCKET NO. LMRX-P036/P1213

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: KIM et al.  
Application No.: 10/813,913  
Filed: 3/30/2004

Examiner: PERT, Evan T.  
Group No.: 2826  
Confirmation No.: 5070

Title: METHODS AND APPARATUS FOR  
INSPECTING CONTACT OPENINGS IN A PLASMA  
PROCESSING SYSTEM

**CERTIFICATE OF MAILING**  
I hereby certify that this correspondence is being deposited with the  
US Postal Service as First Class Mail in a postage-paid envelope  
addressed to the Commissioner for Patents, P.O. Box 1450,  
Alexandria, VA 22313-1450 on April 26, 2005.  
Signed: /Alma Fazlic/  
Alma Fazlic

**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449 may be material to the patentability of the above-identified patent application. Applicants submit the list of these references in compliance with their duty of disclosure pursuant to 37 CFR §§ 1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is believed to be filed before the mailing date of a first Office Action on the merits. If it is determined that fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 50-2284 (Order No. LMRX-P036).

Respectfully submitted,

By: /Joseph Nguyen/  
Joseph Nguyen  
Reg. No. 37,899



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**US PATENT DOCUMENTS**

Examiner Initials	Cite No.	Document Number	Publication Date	Name of Patentee or Applicant	Reference to Related Case
	1	US 5,288,367	1994-02-22	Angell et al.	

**OTHER DOCUMENTS**

Examiner Initials	Cite No.	Description	T
	2	ROBBINS et al., "An Investigation of the Plasma Chemistry Involved in the Synthesis of ZnO by PECVD," Journal of the Electrochemical Society, 150 (10), pp. C693-C698, 2003	
	3	WU et al., "Towards a Complete Plasma Diagnostic System," 4 pages total	
	4	SHUL et al., "Group-III Nitride Etch Selectivity in BCl <sub>3</sub> /Cl <sub>2</sub> ICP Plasmas," 11 pages total, MRS Internet J. Nitride Semicond. Res. 4S1, G8.1 (1999)	

Examiner Signature		Date Considered	
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